

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of	) MAIL STOP AF
Hiroshi Nogami	Group Art Unit: 1763
Application No.: 10/709,622	) Examiner: JEFFRIE ROBERT ) LUND ) Confirmation No.: 3621 )
Filed: May 18, 2004	
For: CVD APPARATUS	
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## **RESPONSE AFTER FINAL REJECTION**

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The Examiner is thanked for the careful examination of the application.

However, in view of the following remarks, the Examiner is respectfully requested to reconsider and withdraw the outstanding rejections.

Claims 1 and 3-14 have been rejected under 35 U.S.C. §103(a) as being obvious over Xu, Kasai, Mashima, Long, and Loan. The specific reference numbers for these documents are set forth on page 2 of the Official Action dated March 7, 2007.

Applicant submits that Xu is not prior art with respect to the present application. However, in view of the fact that one or more of the priority applications of Xu may be prior art, Applicant will respond on the merits.

The Examiner alleges that the motivation for adding a heater to the conductive partition of Xu, as allegedly taught by Kasai, is to heat the processing gas to the desired temperature prior to the gas entering the processing vessel and to prevent thermal shock of the heated substrate when it is exposed to processing gas